

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re the Application of:

CHIWOE WAYNE LO, ET AL.

Application No.:

Filed:

For: **Method and Apparatus for Multiple  
Charged Particle Beams**

Art Group: 2861

Examiner: Judy Nguyen

**INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. §1.97**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In accordance with the duty of disclosure, enclosed is a copy of Information Disclosure Statement by Applicant (form PTO/SB/08), which is being submitted concurrently with the Divisional Application. It is respectfully requested that the cited references be considered and that the enclosed copy of PTO/SB/08 be initialed by the Examiner to indicate such consideration and a copy thereof returned to applicant(s). Some or all of the references listed on the enclosed PTO/SB/08 were previously identified in the parent application (Application No. 09/898,318, filed July 2, 2001) and copies of the references were furnished at that time. Accordingly, per 37 CFR §1.98(d)(1) additional copies of those references are not submitted herewith.

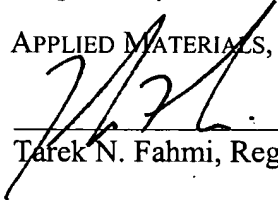
The submission of this Information Disclosure Statement is not to be construed as a representation that a search has been made in the subject application and is not to be construed as an admission that the information cited in this statement is material to patentability.

Please charge any fees due to Deposit Account 02-2666. A duplicate copy of the Fee Transmittal (PTO/SB/17) is enclosed for this purpose.

Respectfully submitted,

APPLIED MATERIALS, INC.

Date: April 15, 2004

  
Tarek N. Fahmi, Reg. No. 41,402

Patent Counsel  
P.O. Box 450A  
Santa Clara, CA 95052  
Telephone: (408) 947-8200

Send To: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450

Substitute for form 1449A/PTO

# **INFORMATION DISCLOSURE STATEMENT BY APPLICANT**

Sheet 2 of 2

**Complete if Known**

Application Number  
Filing Date  
First Named Inventor Chiwoe Wayne Lo  
Art Unit 2861  
Examiner Name Judy Nguyen  
Attorney Docket Number 6317P090D2

## **NON PATENT LITERATURE DOCUMENTS**

Examiner Initials*	Cite No.†	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T²
		T.R. GROVES, et al., "Distsributed, multiple variable shaped electron beam column for high throughput maskless lithography", J. Vac. Sci. Technol., B 16(6), Nov/Dec 2000, pp. 3168-3173	
		E. YIN, et al., "Electron optical column for a multicolumn, multibeam direct-write electron beam lithography system", J. Vac. Sci. Technol., B 18(6), Nov/Dec 2000, pp. 3126-3131	
		A. KHURSHEE, "Permanent magnet objective lenses for multicolumn electron-beam systems", Review of Scientific Instruments, Vol. 72, Number 4, April 2001, pp. 2106-2109	
		EIICHI GOTO et al., "MOL (moving objective lens) Formulation of deflective aberration free system", Optik, 48 (1977), No. 3, pp. 255-270	

Examiner Signature	Date Considered
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\*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication.

†Applicant's unique citation designation number. ²Applicant is to place a check mark here if English language Translation is attached.

Based on PTO/SB/08B (08-03) as modified by Blakely, Solokoff, Taylor & Zafman (wlr) 08/11/2003.  
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